

Docket Number: 081468-0309012
Client Reference: P-1840.000-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

ZAAL et al.

Group Art Unit: 2812

Application No.: 10/814,815

Examiner: Unassigned

Filed: April 1, 2004

Confirmation No.: 5302

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

September 7, 2004


INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. 1.56, the attention of the Patent and Trademark Office is hereby directed to the following U.S. patent application(s):

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	DE SMIT (081468-0309173)	10/820,227	04/08/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	DE SMIT (081468-0309978)	10/860,662	06/04/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	DUINEVELD et al. (081468-0308101)	10/773,461	02/09/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	FLAGELLO et al. (081468-0302644)	10/698,012	10/31/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	DE SMIT et al. (081468-0306530)	10/705,804	11/12/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	LOF et al. (081468-0306781)	10/705,805	11/12/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	LOF et al. (081468-0306524)	10/705,783	11/12/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	VAN SANTEN et al. (081468-0307331)	10/743,271	12/23/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	MULKENS et al. (081468-0307333)	10/743,266	12/23/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	DERKSEN et al. (081468-0306526)	10/705,785	11/12/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	SIMON et al. (081468-0307087)	10/724,402	12/01/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	BLEEKER (081468-0306527)	10/715,116	11/18/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	STREEFKERK et al. (081468-0306882)	10/719,683	11/24/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	LOF et al. (081468-0306525)	10/705,816	11/12/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	DIERICHS (081468-0308270)	10/775,326	02/11/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	LOF et al. (081468-0309957)	10/857,614	06/01/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	SUWA et al. (Reissue Application of U.S. Patent No. 6,191,429 B1)	10/367,910	02/19/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input type="checkbox"/> Other: stamped receipt card
	KOLESNYCHENHO et al. (081468-0309196)	10/823,777	04/14/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card

*The Examiner's initials adjacent a citation indicates he/she has considered the cited application relative to the subject application.

It is respectfully requested that these applications and the art cited therein during examination be expressly considered during the prosecution of this application and be made of record in this application. The identification of the above U.S. patent applications is not to be construed as a waiver of secrecy as to those applications now or upon issuance of the present application as a patent.

PLEASE DO NOT PRINT the above information on the patent which results from this application.

Consideration of each listed application is earnestly solicited since unpublished patent applications are contemplated as IDS material; see the exception in Rule 98(a)(2)(iii) and note the penultimate sentence of MPEP 609.

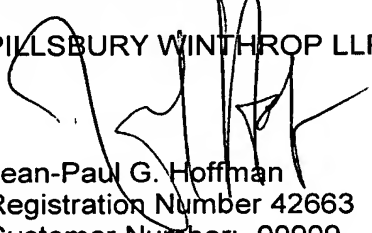
Further, in keeping with MPEP 609, subsec. C(2), 2nd para., line 10 to end of the paragraph (especially note lines 18-25) **PLEASE RETURN A COPY OF THIS LETTER** with the Examiner's initials adjacent each above listing so that applicant will know that each listed application has been considered as required by PTO policy.

Secondly, please consider each document which is listed on the attached Form PTO-1449 and return a copy of that form with the Examiner's initials adjacent each citation, a copy of each document enclosed except for any U.S. patents and published patent applications. It is respectfully requested that these documents listed on the Form PTO-1449 be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

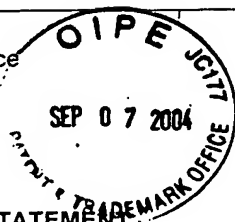
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Date: September 7, 2004



Atty. Dkt. No.	M#	Client Ref.
	309012	P-1840.000-US
Applicant: ZAAL et al.		
Appln. No. 10/814,815		
Filing Date: April 1, 2004		
Examiner: Unknown		Group Art Unit: 2812

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Date: September 7, 2004 Page 1 of 4

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	3,573,975	04/1971	DHAKA <i>et al.</i>	117	212	
	BR	3,648,587	03/1972	STEVENS	95	44	
	CR	4,346,164	08/1982	TABARELLI <i>et al.</i>	430	311	
	DR	4,390,273	06/1983	LOEBACH <i>et al.</i>	355	125	
	ER	4,396,705	08/1983	AKEYAMA <i>et al.</i>	430	326	
	FR	4,480,910	11/1984	TAKANASHI <i>et al.</i>	355	30	
	GR	4,509,852	04/1985	Tabarelli <i>et al.</i>	355	30	
	HR	5,040,020	08/1991	RAUSCHENBACH <i>et al.</i>	355	53	
	IR	5,121,256	06/1992	CORLE <i>et al.</i>	359	664	
	JR	5,610,683	03/1997	TAKAHASHI	355	53	
	KR	5,715,039	02/1998	FUKUDA <i>et al.</i>	355	53	
	LR	5,825,043	10/1998	SUWA	250	548	
	MR	5,900,354	05/1999	BATCHELDER	430	395	
	NR	6,191,429	02/2001	SUWA	250	548	

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclosed	No
	OR	WO 99/49504	09/1999	PCT	Fukami <i>et al.</i>	X		X	
	PR	EP 0023231	02/1981	EUROPE	TABARELLI <i>et al.</i>	X			
	QR	EP 0418427	03/1991	EUROPE	MIYAKE	X		X	
	RR	EP 1039511	09/2000	EUROPE	MURAKAMI <i>et al.</i>	X		X	
	SR	DD 224448	07/1985	GERMANY	HESSE <i>et al.</i>		X		
	TR	DD 242880	02/1987	GERMANY	KUCH		X		
	UR	FR 2474708	07/1981	FRANCE	LETELLIER		X		
	VR	JP 62-065326	03/1987	JAPAN	MORIUCHI	X			
	WR	JP 62-121417	06/1987	JAPAN	NAKAZAWA	X			
	XR	JP 63-157419	06/1988	JAPAN	NAKASUJI	X			
	YR	JP 04-305915	10/1992	JAPAN	OZEKI <i>et al.</i>	X			
	ZR	JP 04-305917	10/1992	JAPAN	OZEKI <i>et al.</i>	X			
	AAR	JP 06-124873	05/1994	JAPAN	TAKAHASHI	X		X	

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

BBR	M. SWITKES et al., "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001				
CCR	M. SWITKES et al., "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356				
DDR	M. SWITKES et al., "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002				

Examiner _____ Date Considered: _____

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

FORM PTO-1449 (modified) To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office				Atty. Dkt. No.	M#	Client Ref.	
				309012		P-1840.000-US	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant: ZAAL et al.			
				Appln. No. 10/814,815			
				Filing Date: April 1, 2004			
Date: September 7, 2004		Page	2	of	4	Examiner: Unknown	Group Art Unit: 2812

U.S. PATENT DOCUMENTS							
Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	6,560,032	05/2003	HATANO	359	656	
	BR	6,600,547	07/2003	WATSON et al.			
	CR	6,603,130	08/2003	BISSCHOPS et al.	250	492.1	
	DR	6,633,365	10/2003	SUENAGA	355	53	
	ER	2002/0163629	11/2002	SWITKES et al.	355	53	
	FR	2003/0123040	07/2003	ALMOGY	355	69	
	GR	2003/0174408	09/2003	ROSTALSKI et al.	359	642	
	HR	2004/0000627 A1	01/2004	SCHUSTER			
	IR	2004/0021844 A1	02/2004	SUENAGA			
	JR	2004/0075895 A1	04/2004	LIN	359	380	
	KR	2004/0109237 A1	06/2004	EPPLER et al.			

FOREIGN PATENT DOCUMENTS						English Abstract		Translation Readily Available	
		Document Number	Date MM/YYYY	Country	Inventor Name	Enclosed	No	Enclosed	No
	LR	JP 07-220990	08/1995	JAPAN	FUKUDA et al.	X			
	MR	JP 10-228661	08/1998	JAPAN	KUROKAWA	X			
	NR	JP 10-255319	09/1998	JAPAN	SUENAGA et al.	X			
	OR	JP 10-303114	11/1998	JAPAN	SUWA	X		X	
	PR	JP 10-340846	12/1998	JAPAN	KUDO	X		X	
	QR	JP 2001-091849	04/2001	JAPAN	AIZAKI et al.	X			
	RR	JP 07-132262	05/1995	Japan	HIRAKAWA et al.	X			
	SR	JP 58-202448	11/1983	Japan	KAWAMURA et al.	X			
	TR	WO 2004/019128	03/2004	PCT	OMURA et al.	X		X	
	UR	WO 03/077037	09/2003	PCT	ROSTALSKI et al.	X		X	
	VR	WO 03/077036	09/2003	PCT	SCHUSTER	X			

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)				
	WR	B.J. LIN, "Drivers, Prospects and Challenges for Immersion Lithography", TSMC, Inc., September 2002		
	XR	B.J. LIN, "Proximity Printing Through Liquid", IBM Technical Disclosure Bulletin, Vol.20, No. 11B, April 1978, p. 4997		
	YR	B.J. LIN, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 922, Optical/Laser Microlithography (1988), pp. 256-269		
	ZR	G.W.W. STEVENS, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol.21 008, pp. 68-72		
	AAR	S. OWA et al., "Immersion Lithography; its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003		
	BBR	S. OWA et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 (2003)		

Examiner	Date Considered:
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Date: September 7, 2004 Page <u>3</u> of <u>4</u>								
U.S. PATENT DOCUMENTS								
Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)		Class	Sub Class	Filing Date (if appropriate)
	AR	6,236,634 B1	05/2001	LEE et al.		369	112	
	BR	2002/0020821 A1	02/2002	VAN SANTEN et al.		250	492	
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		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available
						Enclosed	No	Enclosed
	CR	DD 206 607	02/1984	GERMANY	WESTPHAL et al.		X	
	DR	DD 221 563	04/1985	GERMANY	PFORR et al.		X	
	ER	JP 11-176727	07/1999	JAPAN	SHIRAISHI	X		
	FR	JP 2000-058436	02/2000	JAPAN	Fujishima et al.	X		
	GR	WO 2004/053950 A1	06/2004	PCT	OWA	X		
	HR	WO 2004/053951 A1	06/2004	PCT	MAGOME et al.	X		
	IR	WO 2004/053952 A1	06/2004	PCT	MAGOME et al.	X		
	JR	WO 2004/053953 A1	06/2004	PCT	NEI et al.	X		
	KR	WO 2004/053954 A1	06/2004	PCT	NEI et al.	X		
	LR	WO 2004/053955 A1	06/2004	PCT	HIRUKAWA et al.	X		
	MR	WO 2004/053956 A1	06/2004	PCT	NAGASAKA et al.	X		
	NR	WO 2004/053957 A1	06/2004	PCT	HIDAKA et al.	X		
	OR	WO 2004/053958 A1	06/2004	PCT	MIZUTANI et al.	X		
	PR	WO 2004/053959 A1	06/2004	PCT	SHIRAI	X		
	QR	WO 2004/053596 A2	06/2004	PCT	GRAUPNER	X		
OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)								
	RR	Nikon Precision Europe GmbH, "Investor Relations – Nikon's Real Solutions", May 15, 2003						
	SR	H. KAWATA et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-36						
	TR	J.A. HOFFNAGLE et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B., Vol. 17, No. 6, November/December 1999, pp. 3306-3309						
	UR	B.W. SMITH et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003						
	VR	H. KAWATA et al., "Fabrication of 0.2µm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens", Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177						
	WR	G. OWEN et al., "1/8µm Optical Lithography", J. Vac. Sci. Technol. B., Vol. 10, No. 6, November/December 1992, pp. 3032-3036						
	XR	H. HOGAN, "New Semiconductor Lithography Makes a Splash", PHOTONICS SPECTRA, Photonics TechnologyWorld, October 2003 Edition, pgs. 1-3						
	YR	S. OWA and N. NAGASAKA, "Potential Performance and Feasibility of Immersion Lithography", NGL Workshop 2003, July 10, 2003, Slide Nos. 1-33.						
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U.S. PATENT DOCUMENTS								
Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)		Class	Sub Class	Filing Date (if appropriate)
	ZR	2004/0119954	06/2004	KAWASHIMA et al.		355	30	
	AAR	2004/0125351	07/2004	KRAUTSCHIK et al.		355	53	
	BBR							
	CCR							
	DDR							
	EER							
	FFR							
	GGR							
	HHR							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available
						Enclosed	No	Enclosed
	IIR	WO 2004/055803 A1	07/2004	PCT	VAN SANTEN	X		X
	JJR	WO 2004/057589 A1	07/2004	PCT	NEIJZEN et al.	X		X
	KKR	WO 2004/057590 A1	07/2004	PCT	VAN SANTEN et al.	X		X
	LLR	JP 2004-193252	07/2004	Japan	Not Available	X		
	MMR							
	NNR							
	OOR							
	PPR							
OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)								
	QQR	S. OWA et al., "Update on 193nm immersion exposure tool", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-51						
	RRR	H. HATA, "The Development of Immersion Exposure Tools", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-22						
	SSR	T. MATSUYAMA et al., "Nikon Projection Lens Update", SPIE Microlithography 2004, 5377-65, March, 2004						
	TTR	"Depth-of-Focus Enhancement Using High Refractive Index Layer on the Imaging Layer", IBM Technical Disclosure Bulletin, Vol. 27, No. 11, April 1985, p. 6521						
	UUR	A. SUZUKI, "Lithography Advances on Multiple Fronts", EEdesign, EE Times, January 5, 2004						
	VVR	B. LIN, "The k_3 coefficient in nonparaxial λ /NA scaling equations for resolution, depth of focus, and immersion lithography, <i>J. Microlith., Microfab., Microsyst.</i> 1(1):7-12 (2002)						
	WWI							
	XXR							
	YYR							
	ZZR							
	AAA							
Examiner					Date Considered:			
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.								